

Notice of References Cited			Application/Control No.	Applicant(s)/Patent Under Reexamination	
			10/623,052	FUJII ET AL.	
Examiner		Art Unit		1775	
Jason L. Savage		Page 1 of 2			

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
X	A	US-6,820,795	11-2004	Fujii, Tomoyuki	228/121
X	B	US-6,756,132	06-2004	Fujii et al.	428/642
X	C	US-6,728,091	04-2004	Tsuruta et al.	361/234
X	D	US-6,721,162	04-2004	Weldon et al.	361/234
X	E	US-6,579,623	06-2003	Kurihara et al.	428/556
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
X	U	US Patent Publication 2005/0127619, Tateno et al., Electrostatic Clampless Holder Module and Cooling System 06-2005
X	V	US Patent Publication 2004/0209108, Fujii et al., Joined Structures of Metal Terminals and Ceramic Members, Joined Structures of Metal Members and Ceramic Members, and Adhesive Materials, 10-2004
X	W	US Patent Publication 2003/0011392, Adams et al., Sample Chuck with Compound Construction, 01-2003
X	X	US Patent Publication 2002/0050246, Parkhe, Full Area Temperature Controlled Electrostatic Chuck and Method of Fabrication Same, 05-2002

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination	
		10/623,052	FUJII ET AL.	
Examiner		Art Unit	1775	Page 2 of 2
Jason L. Savage				

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	2003-080375 /	03-2003	JP	Fujii	
	O	2002-293655	10-2002	JP	Fujii et al.	
	P	11-335184	12-1999	JP	Furuoka	
	Q	08-008330	01-1996	JP	----	
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
X	U	US Patent Publication 2001/0026010, Horiuchi et al., Semiconductor Device and Process of Production of Same, 10-2001.
	Y	JP 2003-080375 English Machine Translation, Fujii, Manufacturing Method of Semiconductor Wafer Supporting Member Joined Body and Semiconductor Wafer Supporting Member Joined Body, 03-2003.
	W	JP 08-008330 English Machine Translation, MIYATA GIKEN YG, 01-1996
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.